



Update on 3D-related activities in Pavia/Bergamo

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AIDA





- Status of the new 3D submission
 - The Superpix1 chip: FE for hybrid pixels
 - The ApselVI chip: 3D DNW MAPS

- Test of 3D Tezzaron/GlobalFoudries MAPS prototypes
 - Tests on SDR1 digital circuits
 - Characterization of the APSEL5T-TC analog front-end
 - Effects of ionizing radiation on APSEL5T-TC and single transistors

- Conclusions and plans for the future



2nd 3D Prototype Submission



DNW MAPS
3.25x2 mm²

**Hybrid pixels
single MOS**
3.25x2 mm²

Superpix1, front-end for hybrid
pixels

128x32 pixels

10x3.5 mm²

ApselVI, DNW MAPS matrix
with fast sparsified readout

128x96 pixels

10x5.2 mm²

- The VIPIX collaboration is at an advanced stage in the design work for a second MPW run with the 3D Tezzaron/Globalfoundries process

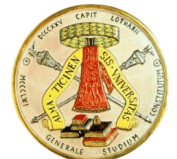
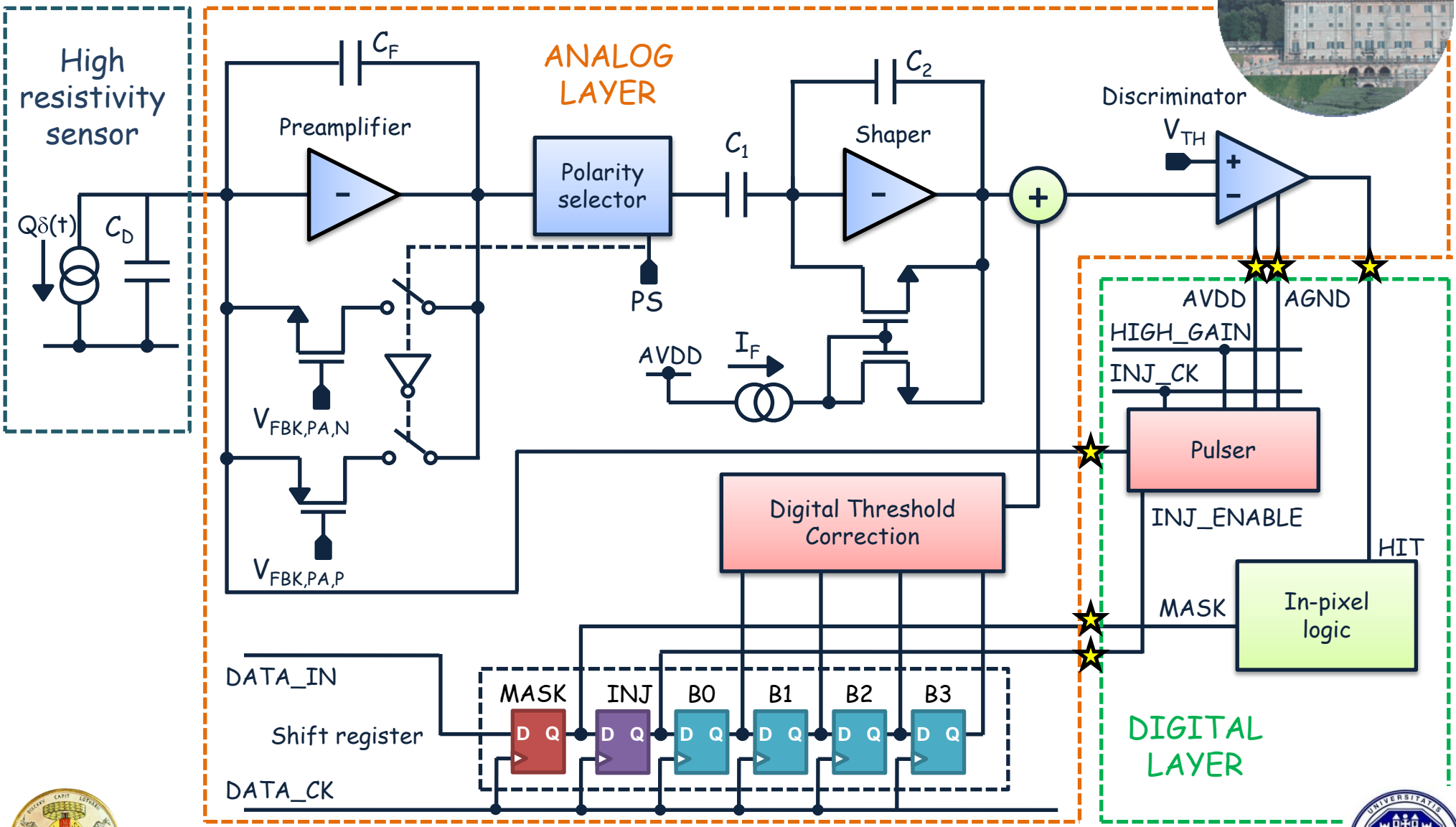
- The Superpix1 chip
- The ApselVI chip

Small test structures:

- Test chip for hybrid pixels
- DNW MAPS test chip



Superpix1 Analog Front-End

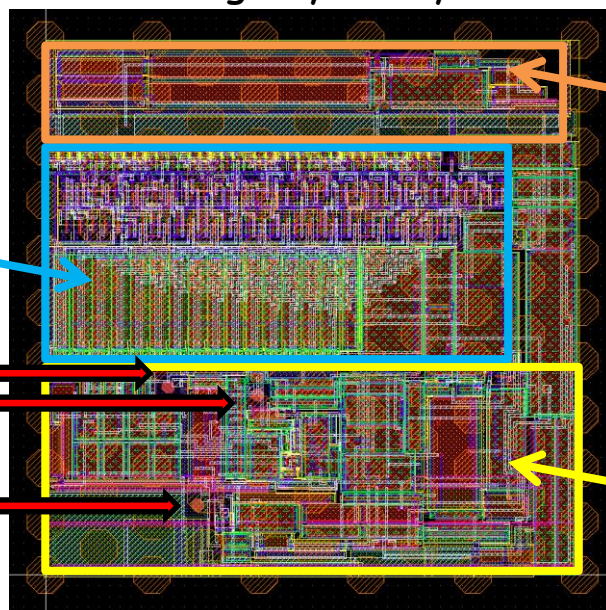


Superpix1 Analog Front-End



Main front-end design features	
Analog Power Dissipation [$\mu\text{W}/\text{pixel}$]	13.5
Peaking Time ($Q_{\text{inject}} = 16000 e^-$) [ns]	250
Charge sensitivity [mV/fC] @ DAC outPUT	48
ENC @ $C_D = 150 \text{ fF}$ [$e^- \text{ rms}$]	180
Threshold dispersion (before/after correction) [$e^- \text{ rms}$]	560/65

Analog Layer Layout



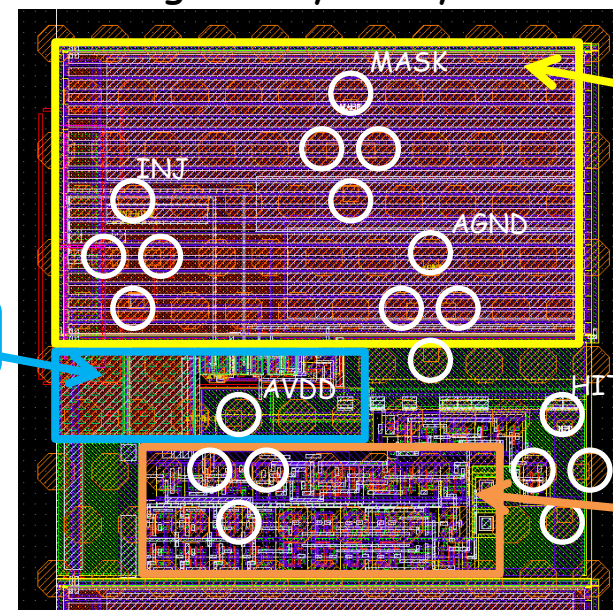
DAC, decoder and shift register

3 connections
PA input -
bump bond pad
(Supercontact)

Discriminator

Preamplifier,
polarity
selector and
shaper blocks

Digital Layer Layout



poly
resistors

Pulser circuit

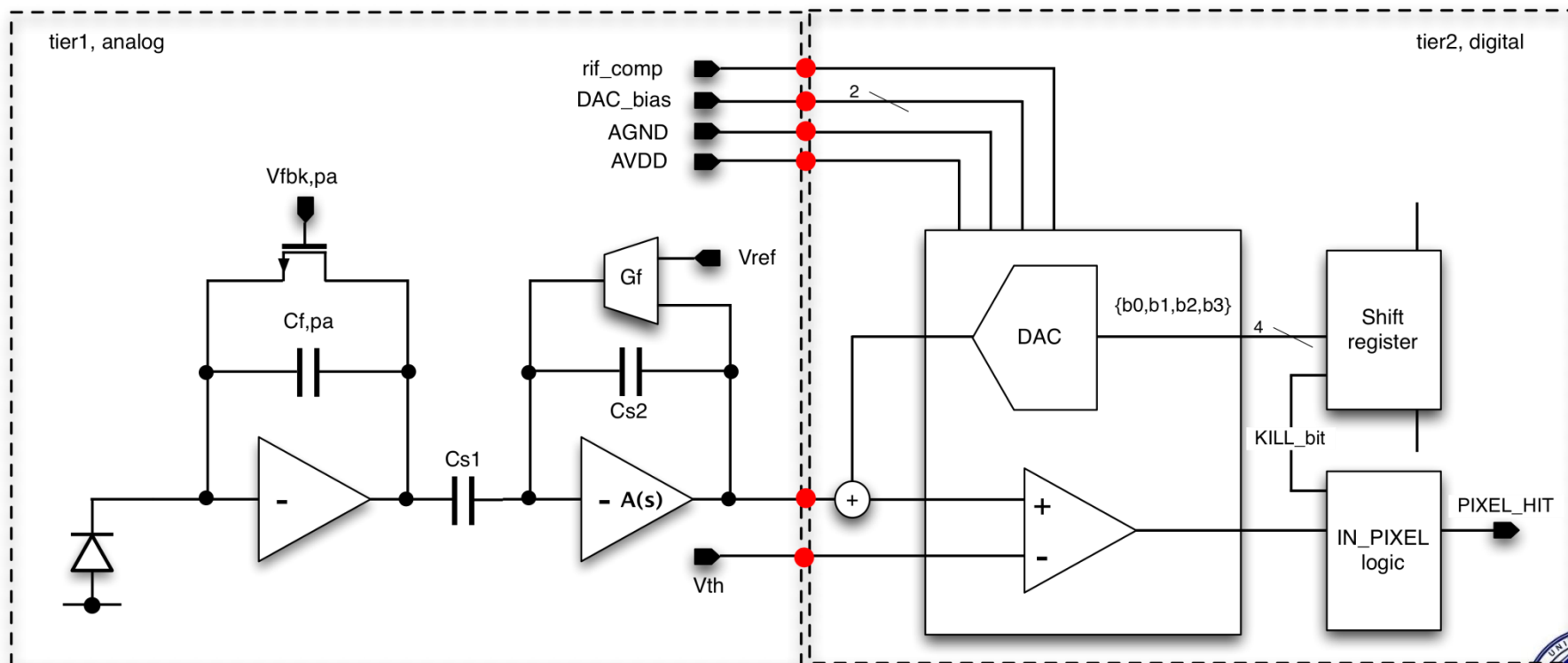
In-pixel logic



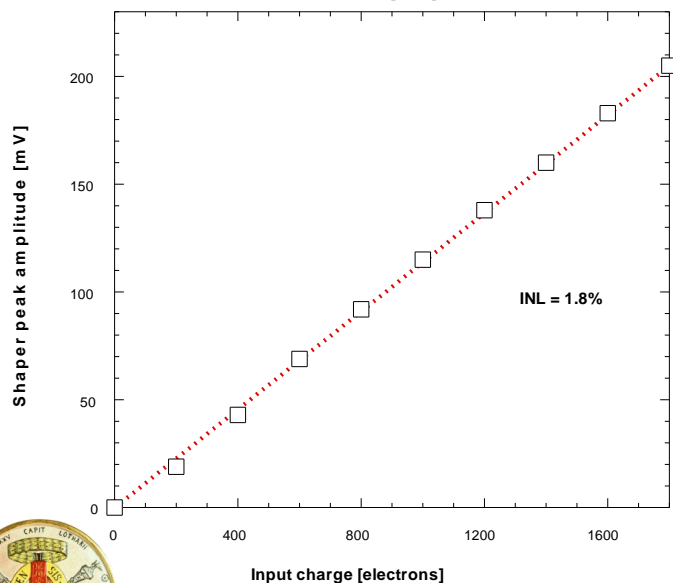
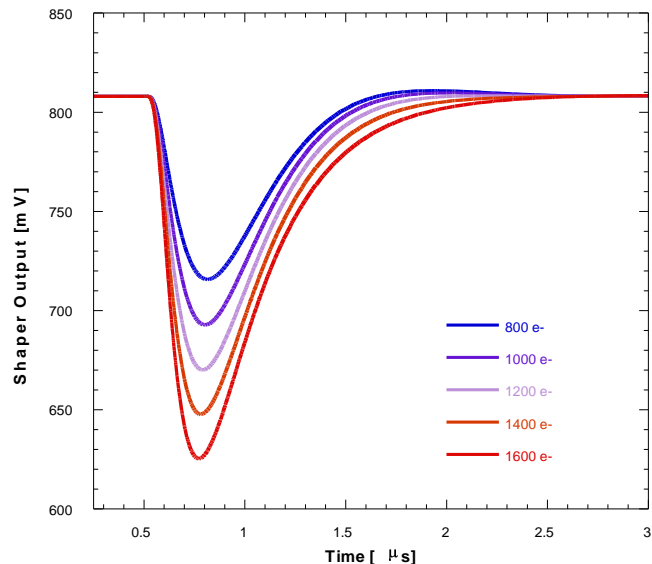
ApelVI front-end architecture



- DNW sensor
- Charge preamplifier with a $C_{f,pa}$ continuously discharged by an NMOS biased in deep subthreshold region
- RC-CR shaper with a transconductor feedback network:
 - V_{ref} chip-wide distributed by an external voltage reference (not affected by voltage drop issues)



ApselVI Main Analog Features



Main front-end design features

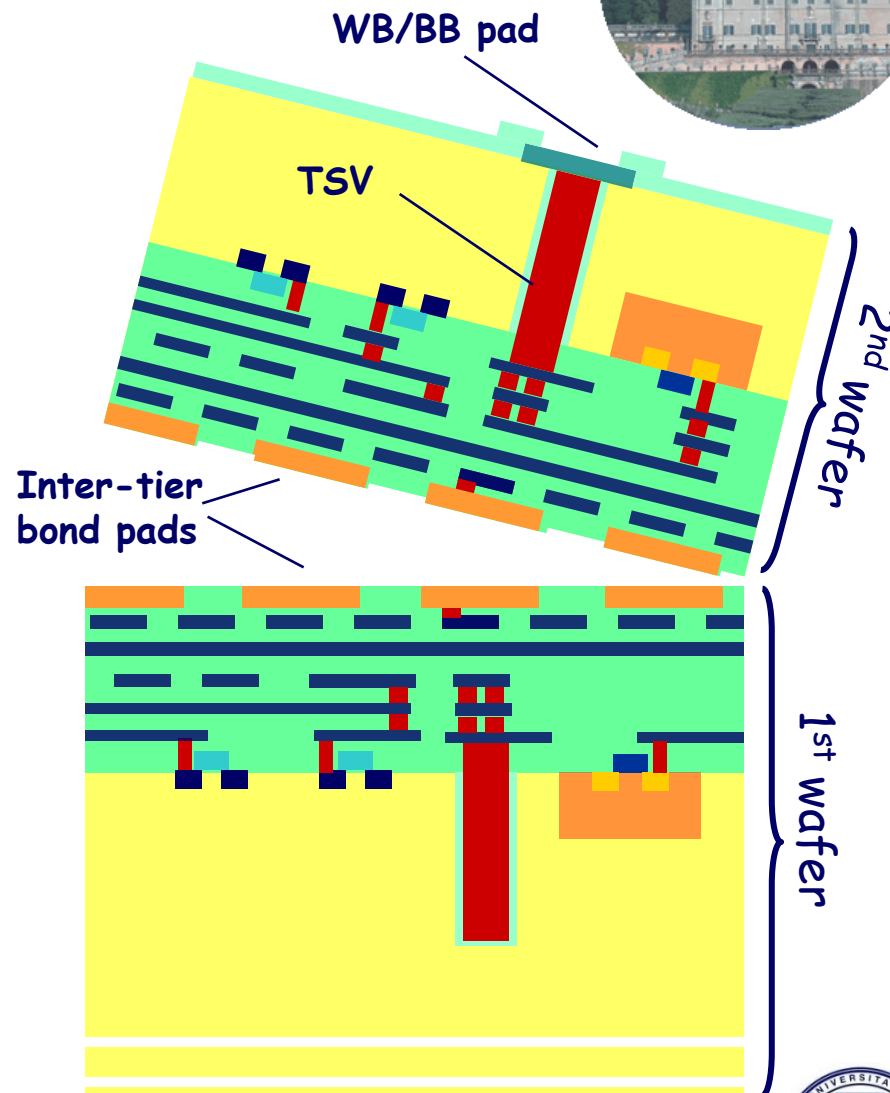
Charge sensitivity [mV/fC] @ DAC outPUT	720
peaking time [ns]	300
ENC @ $C_D=300$ fF [e^- rms]	40
Threshold dispersion before/after correction [e^- rms]	106/15
INL (@ 0/2000 e^-) [%]	1.8
Power consumption [μ W]	36
Pixel pitch [μ m]	50
Matrix size	128x96



1st 3D Tezzaron/Globalfoundries run



- In 2009, the Italian VIPIX collaboration submitted 3D active pixel devices in the first run of the 3DIC Consortium hosted by Fermilab
- In this run, we designed 3D MAPS with two layers ("tiers") of the 130 nm CMOS process by Chartered Semiconductor, vertically integrated with the Tezzaron interconnection technology
- Tests on structures belonging to the first run are ongoing



Tezzaron 3D Test Structures

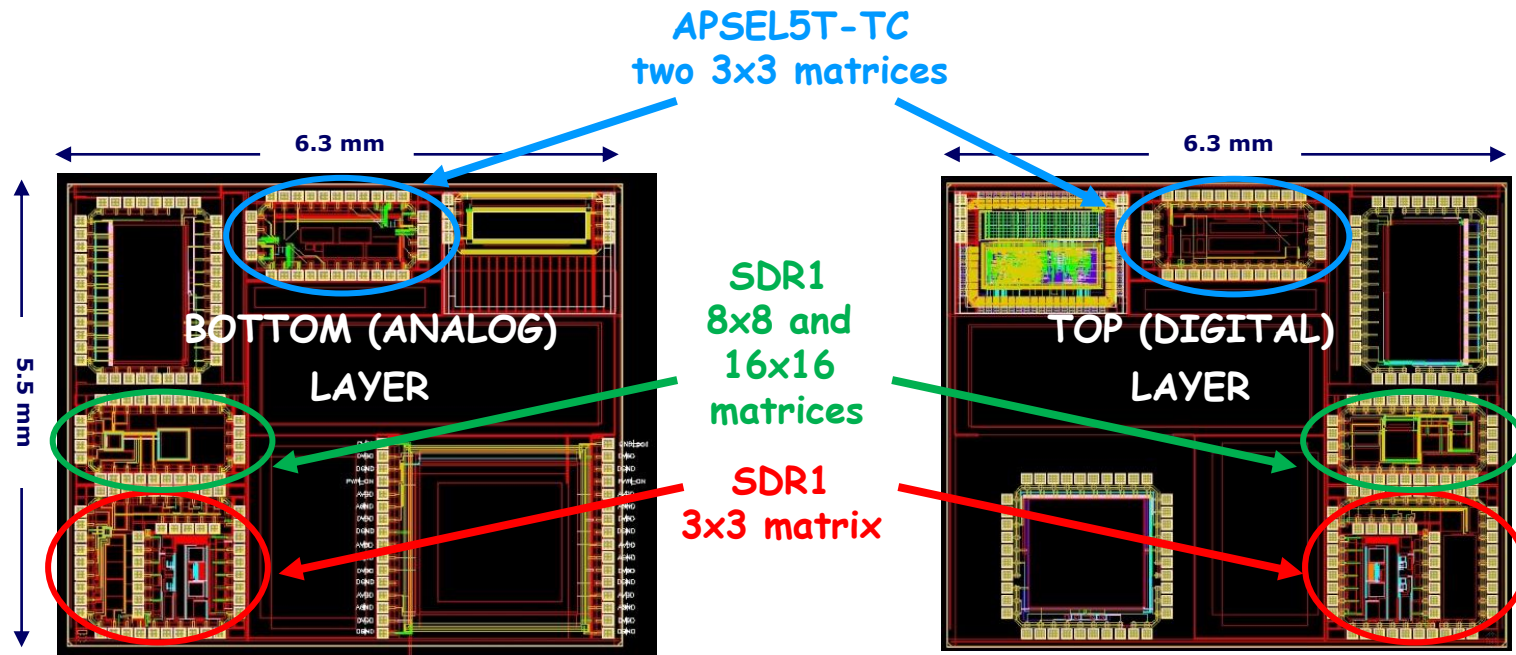


- SDR1 prototype
(Sparsified Digital Readout 1)

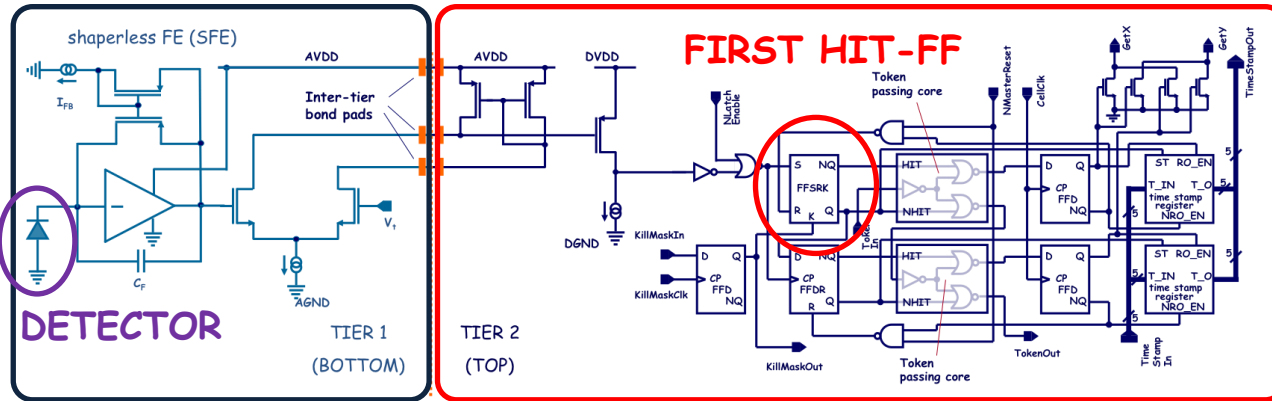
- pitch = 20 μm
- Application: ILC
- FE: shaperless
- DUTs: matrices with sparsified readout

- APSEL5T-TC prototype
(Active Pixel Sensor ELectronics)

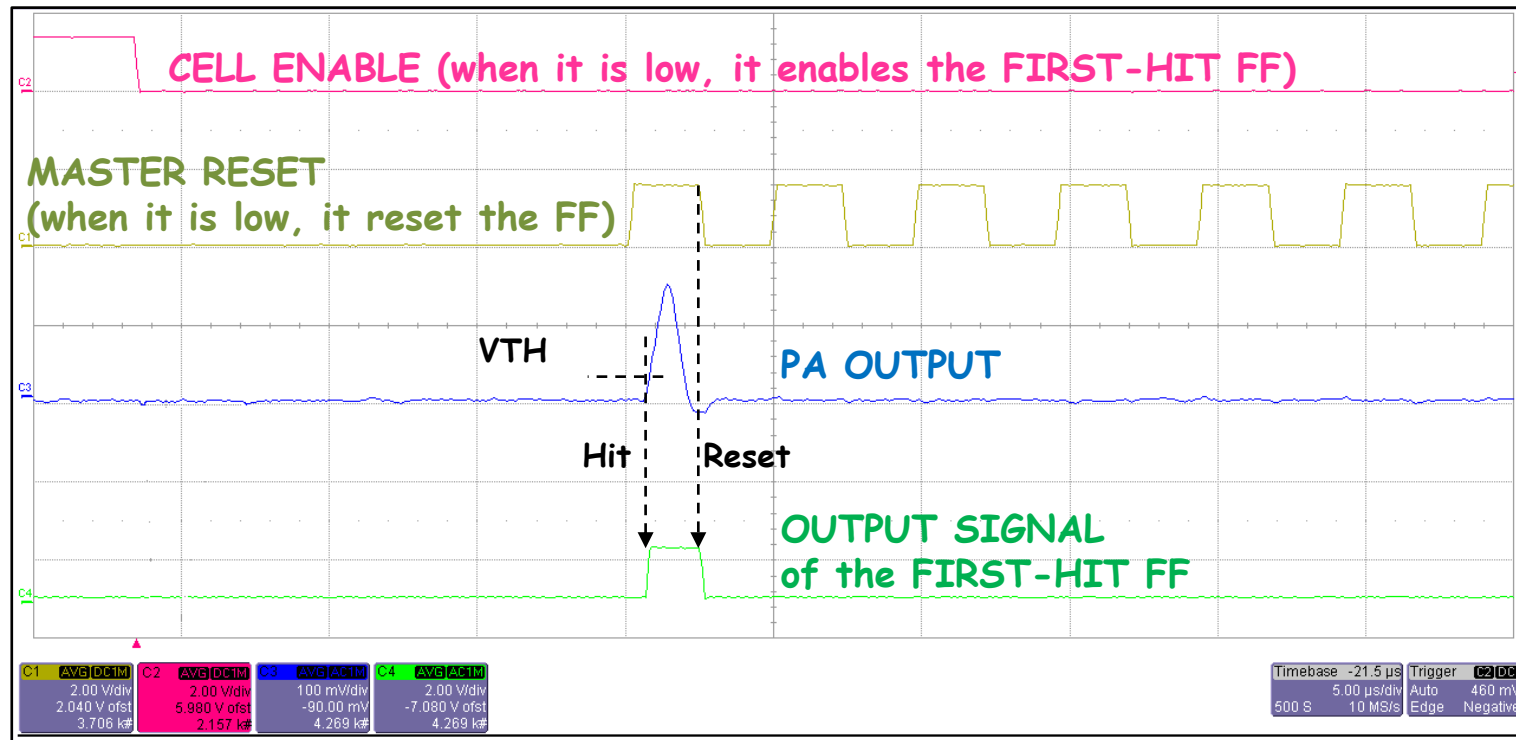
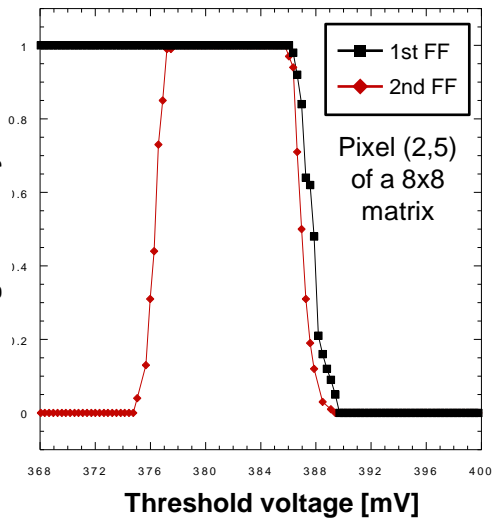
- pitch = 40 μm
- Application: SuperB
- FE: shaperless
- DUTs: 3x3 matrices



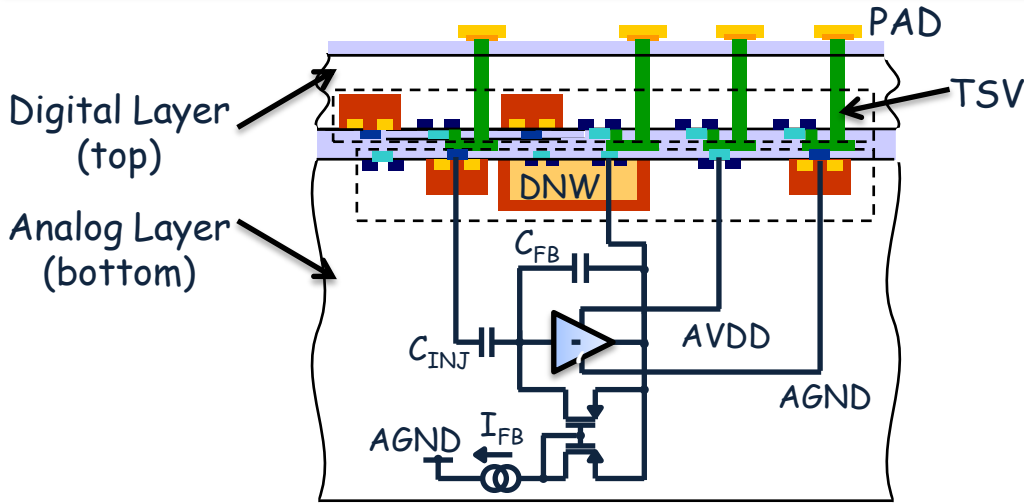
SDR1 chip (Sparsified Digital Readout 1)



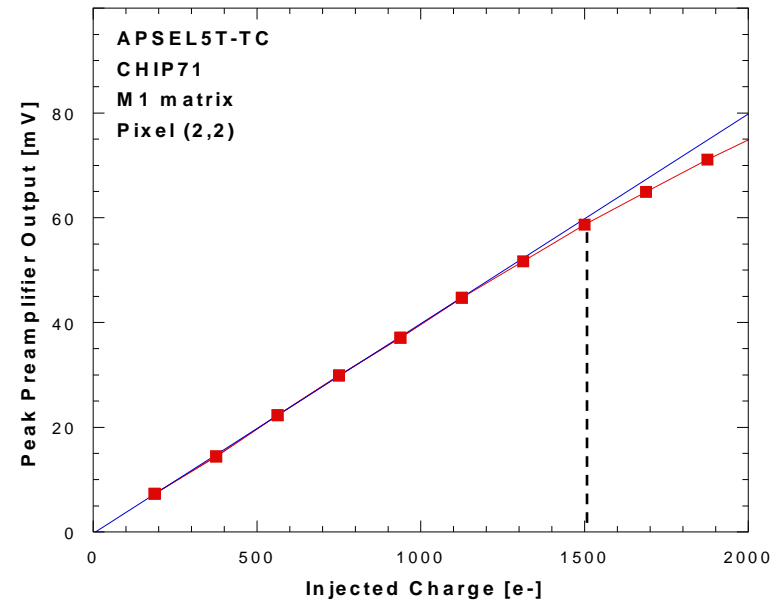
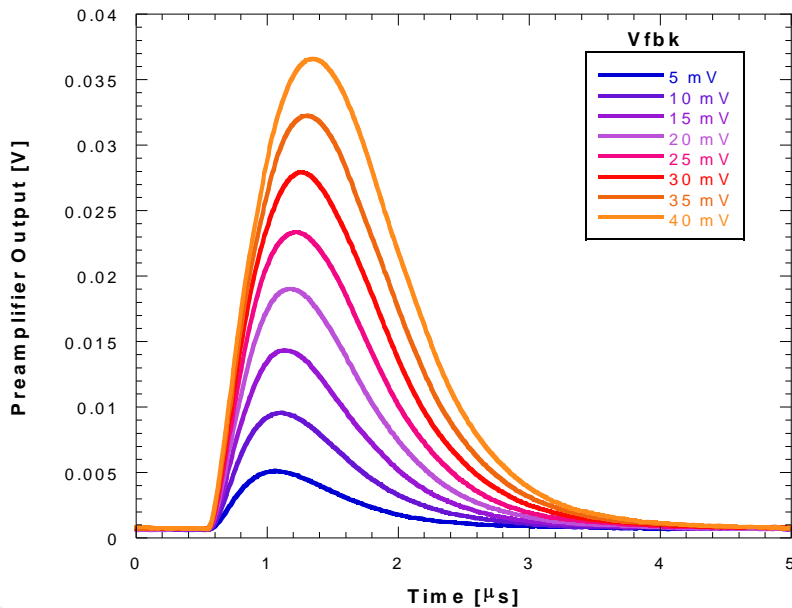
○ Tests on SDR1 digital circuits show the full functionality of vertically integrated chips



APSEL5T-TC Analog Front-End Characterization



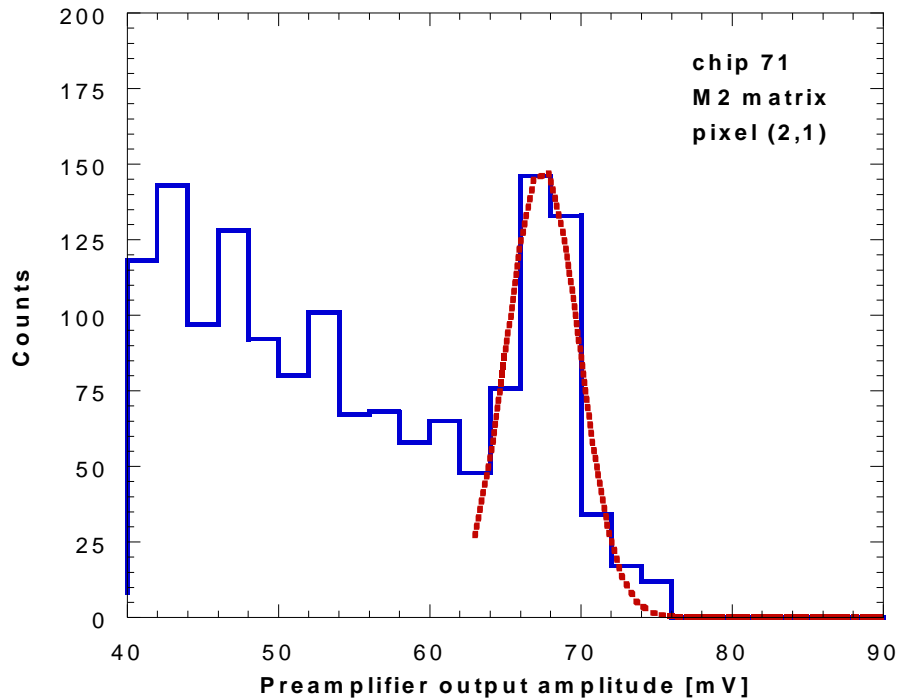
- Charge sensitivity: $\sim 250 \text{ mV/fC}$
- Input dynamic range: $\sim 1500 e^-$
- ENC: $\sim 40 e^- \text{ rms}$



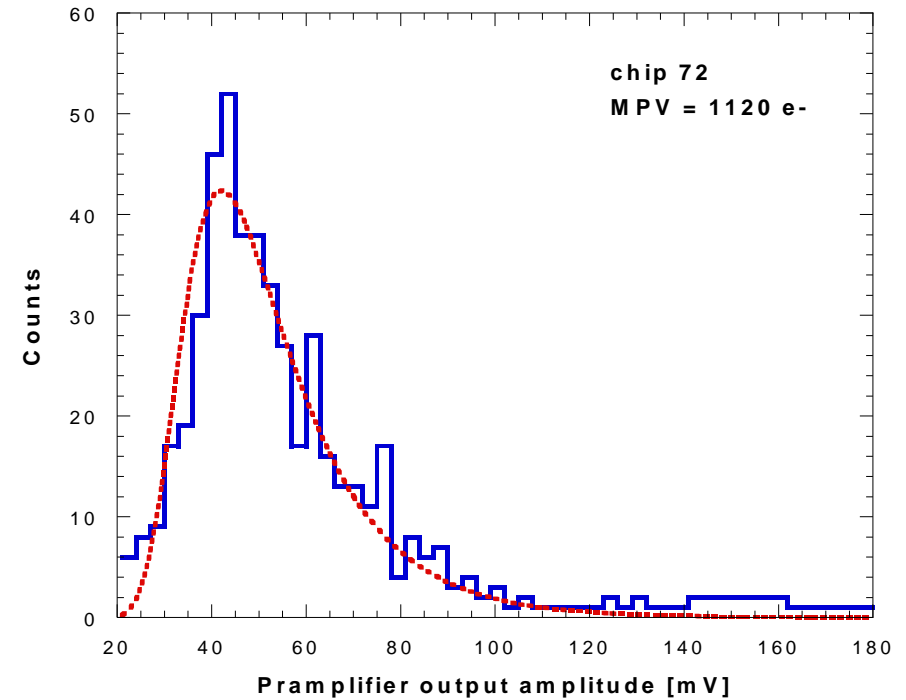
Tests with Radiation Sources



○ Test with ^{55}Fe source



○ Test with ^{90}Sr source



○ Charge sensitivity in good agreement with values obtained by means of charge injection

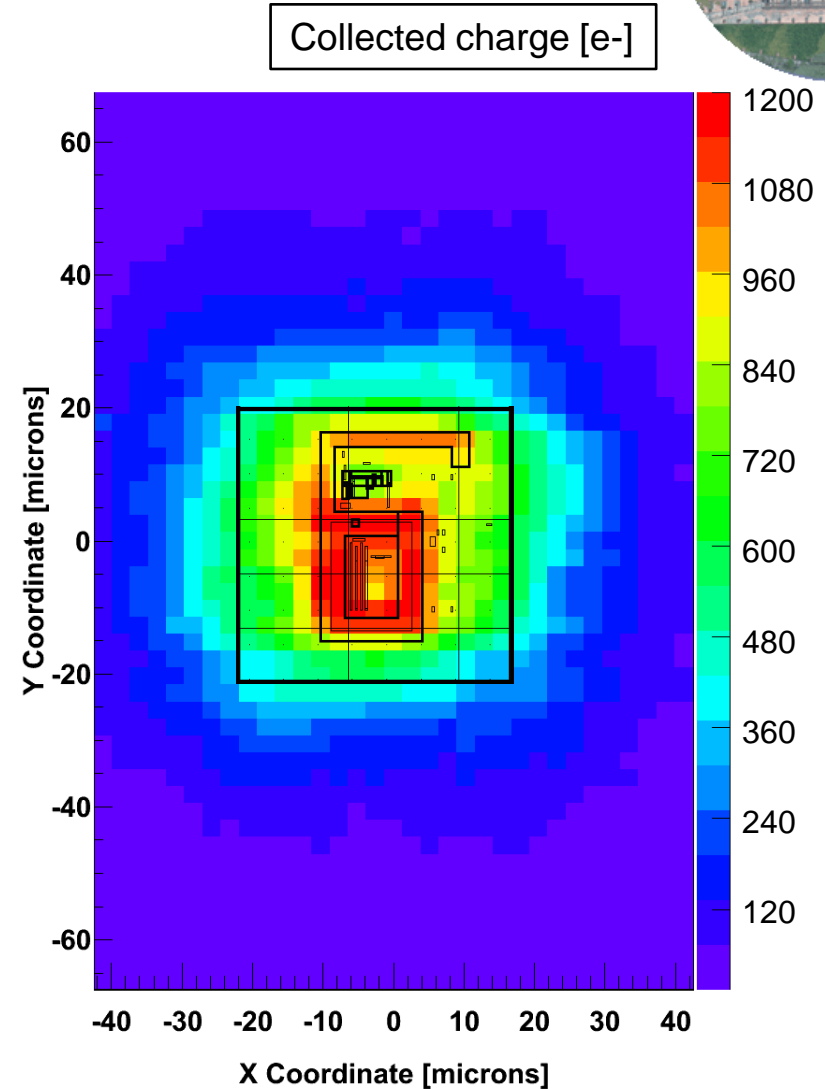
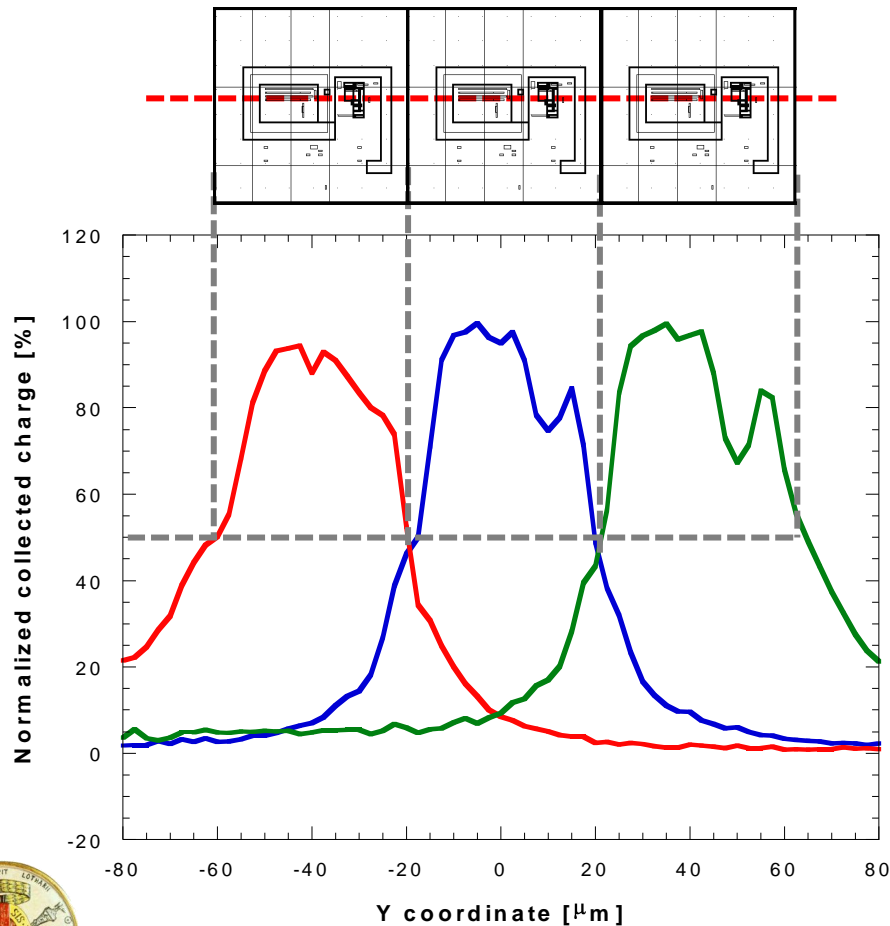
○ M1 matrix - 3x3 cluster signal



Laser Measurements



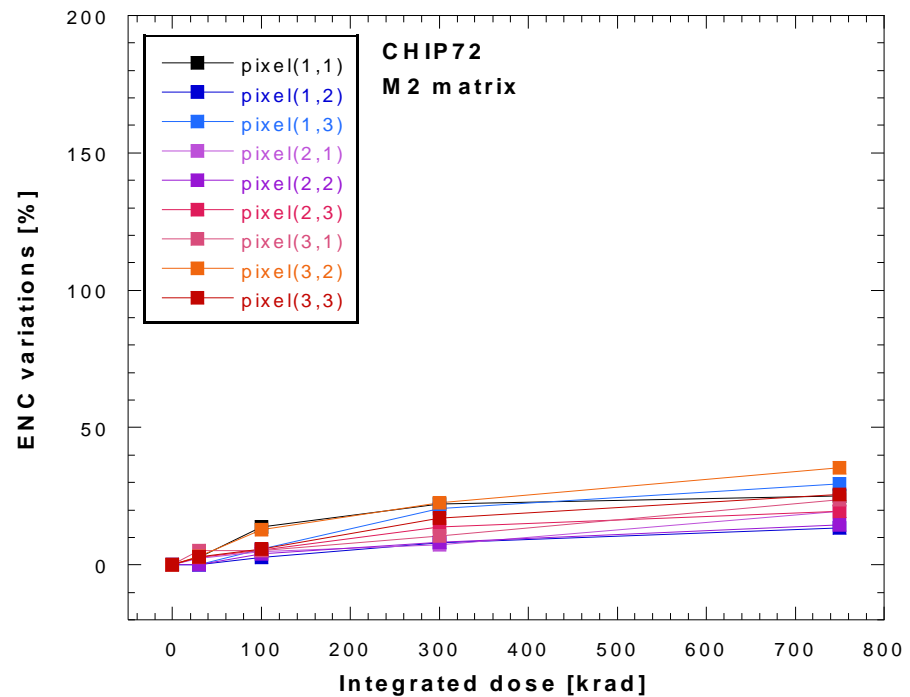
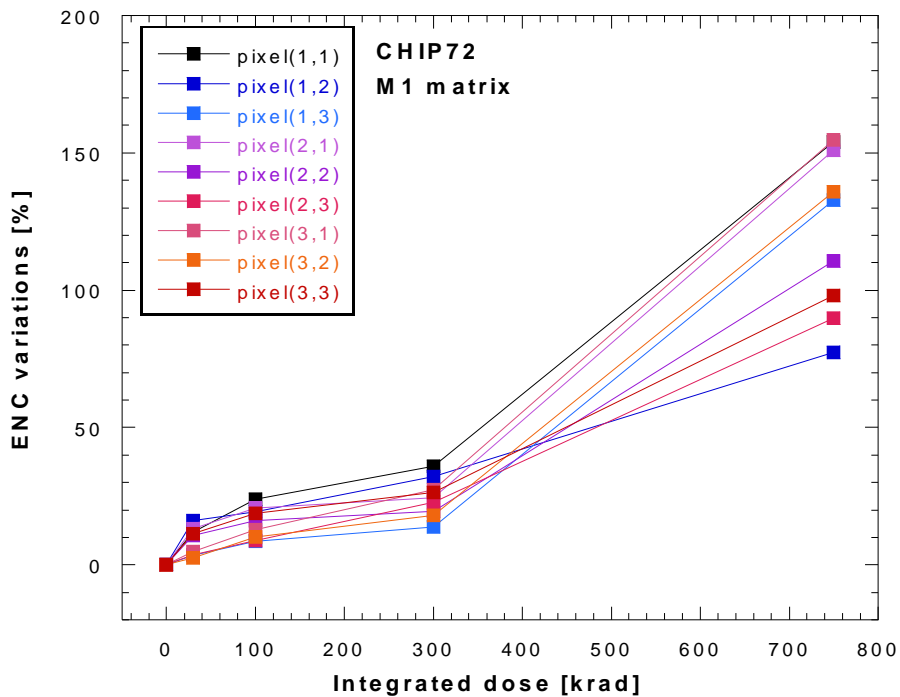
- Normalized collected charge as a function of the IR laser spot position ($\lambda=1064\text{nm}$)



Effects of ionizing radiations on ENC



- The irradiation campaign has been performed with a ^{60}Co source up to a total dose of about 750 krad



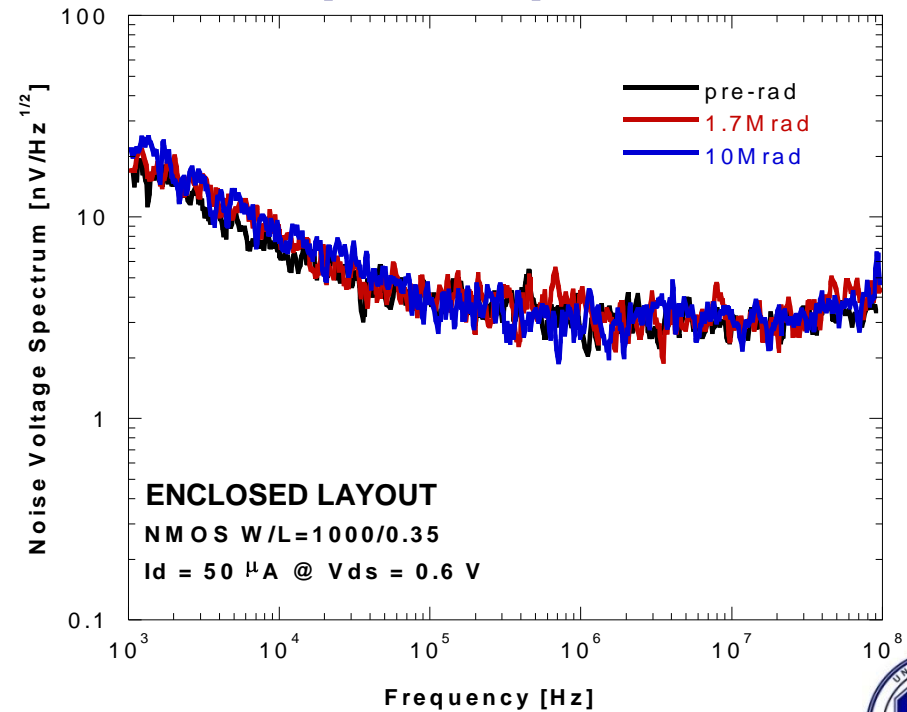
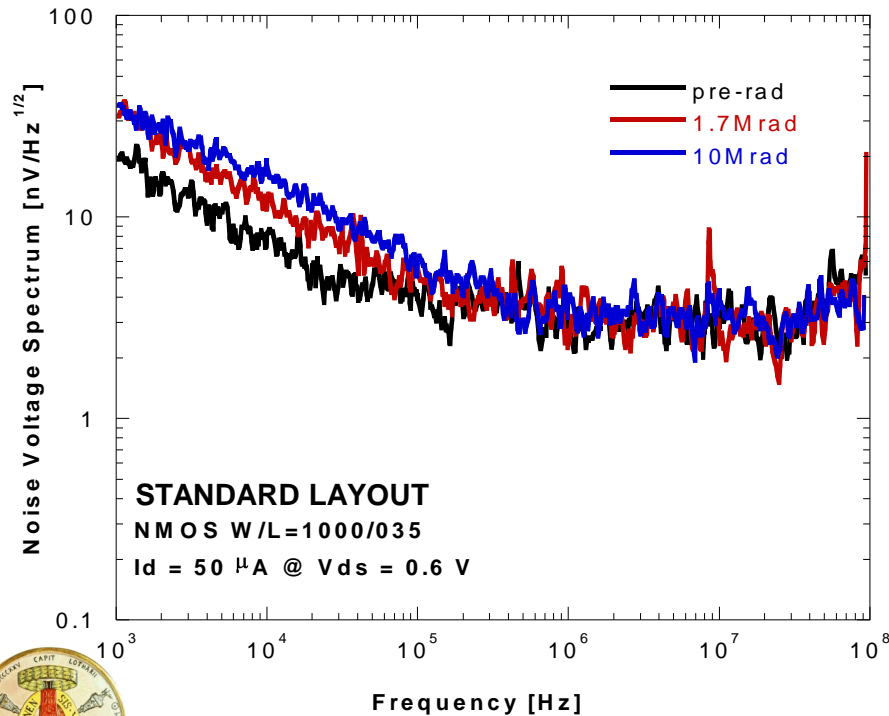
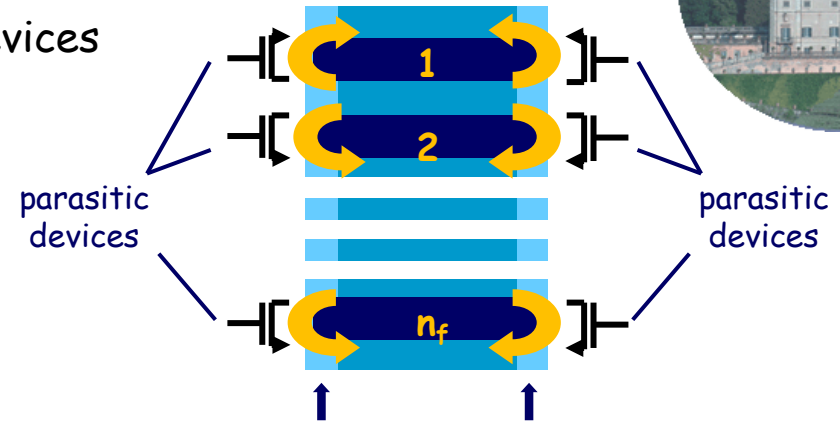
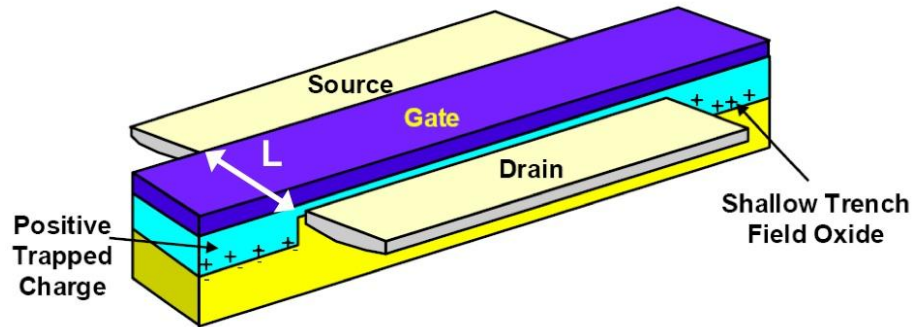
- M1 matrix: PA with standard layout input transistor

- M2 matrix: PA with enclosed layout input transistor



Effects on noise in single devices

- $1/f$ noise increase due to lateral parasitic devices



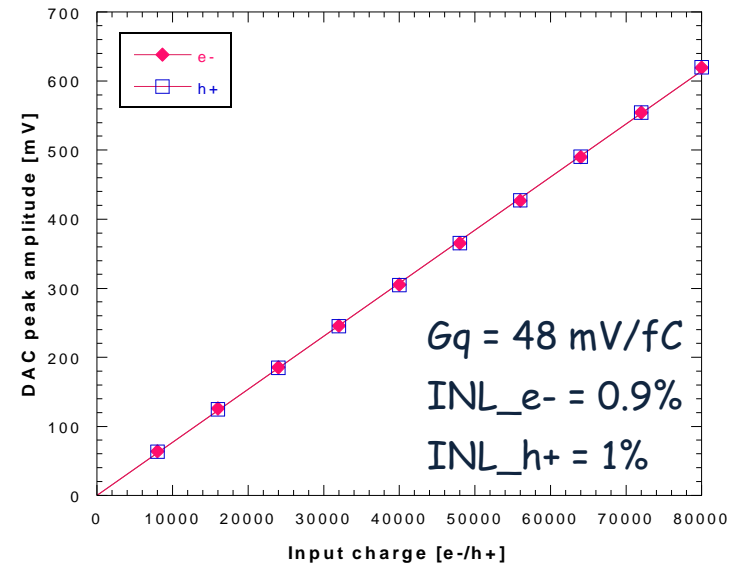
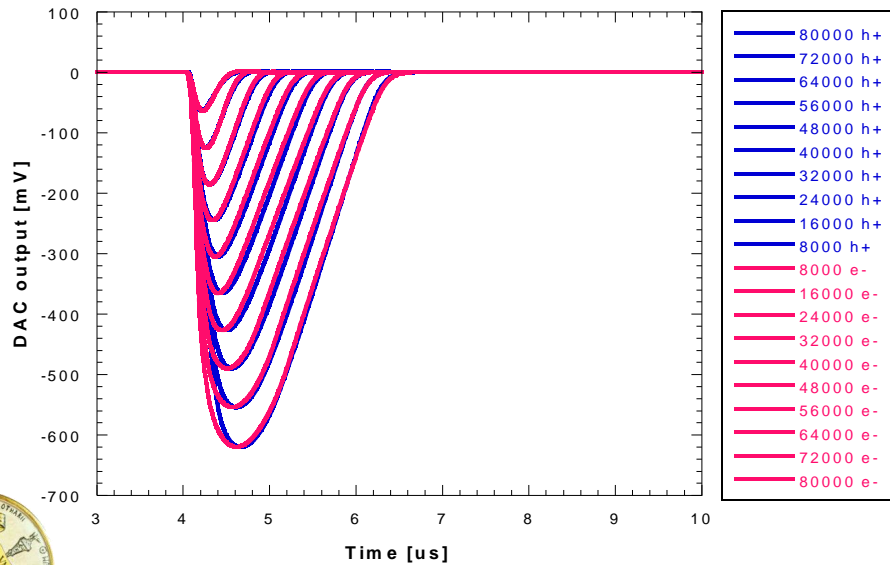
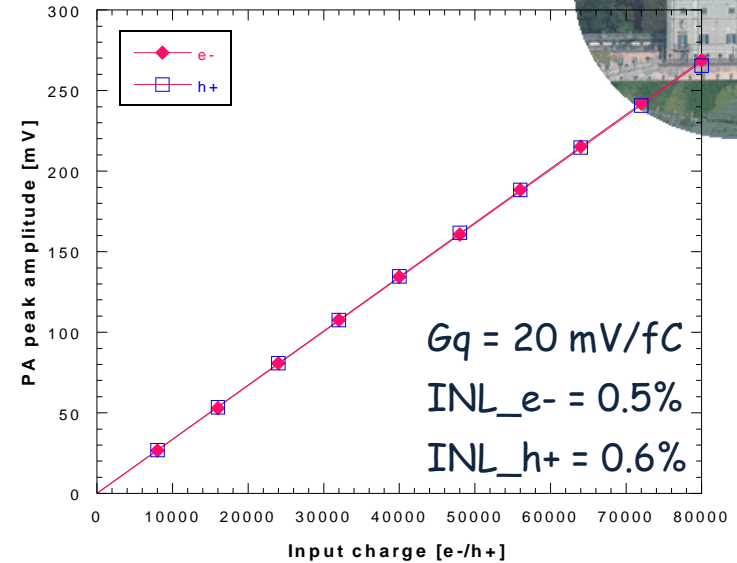
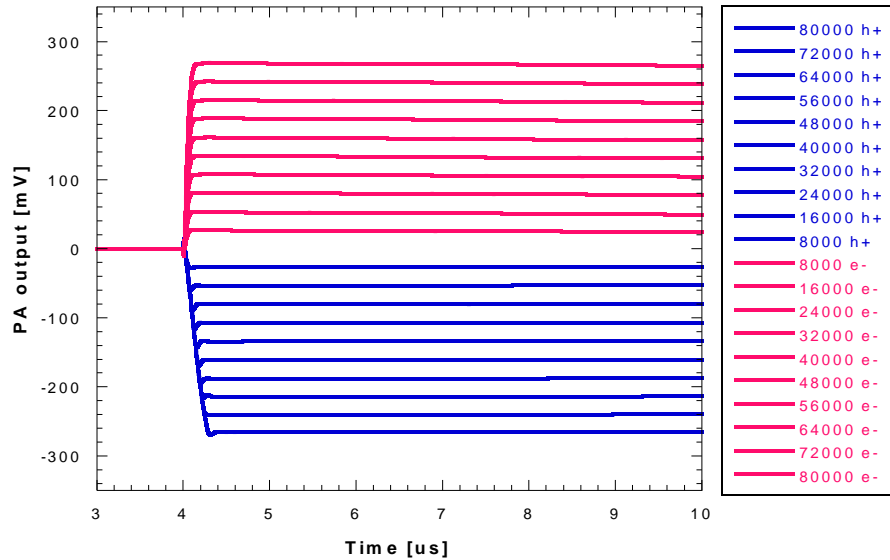
Conclusions and plans for the future



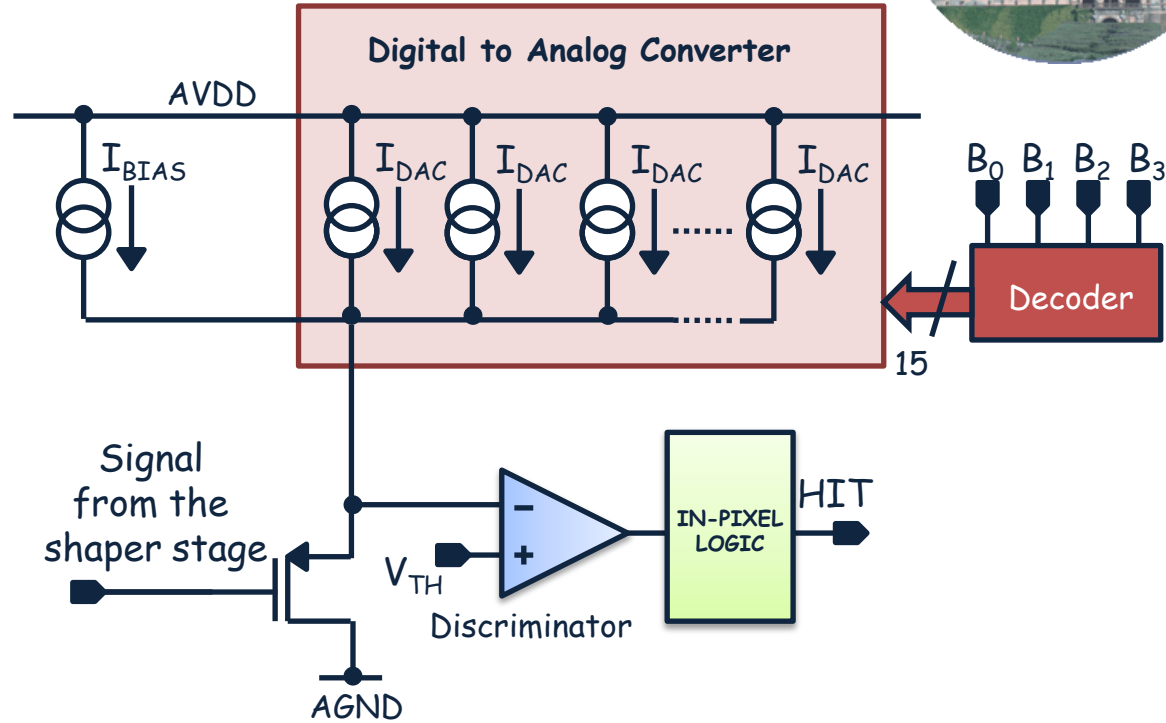
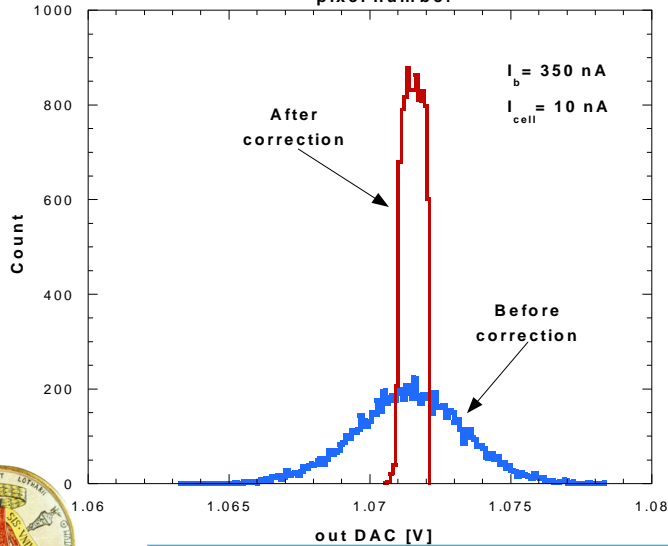
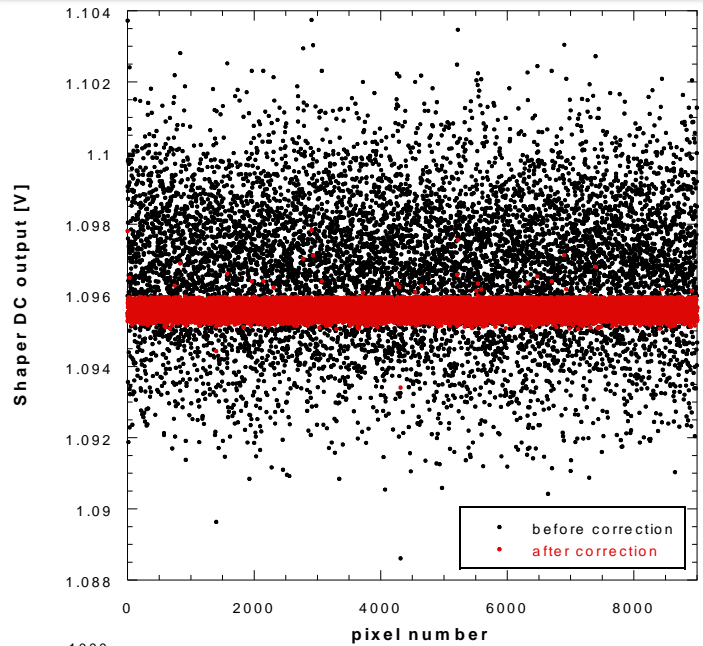
- Two different approaches have been considered for the design of the readout chip in view of applications to the SVT Layer0 of the SuperB factory
- ApseVI and SuperPIX1 will be fabricated in the Tezzaron-Globalfoundries 130 nm 3D CMOS technology (to be submitted Q1 2013)
- Tests on the SDR1 digital circuits pointed out the full functionality of the prototypes designed in the Tezzaron/Globalfoundries 3D technology
- APSEL5T-TC charge collection properties have been characterized by means of radiation sources and IR laser. Radiation hardness tests (γ -rays) have been performed also on single transistors
 - Significant increase in equivalent noise charge
 - ELT are required to avoid excessive 1/f noise increase
- Measurements on 3D prototypes are still in progress



Superpix1 Analog Front-End features



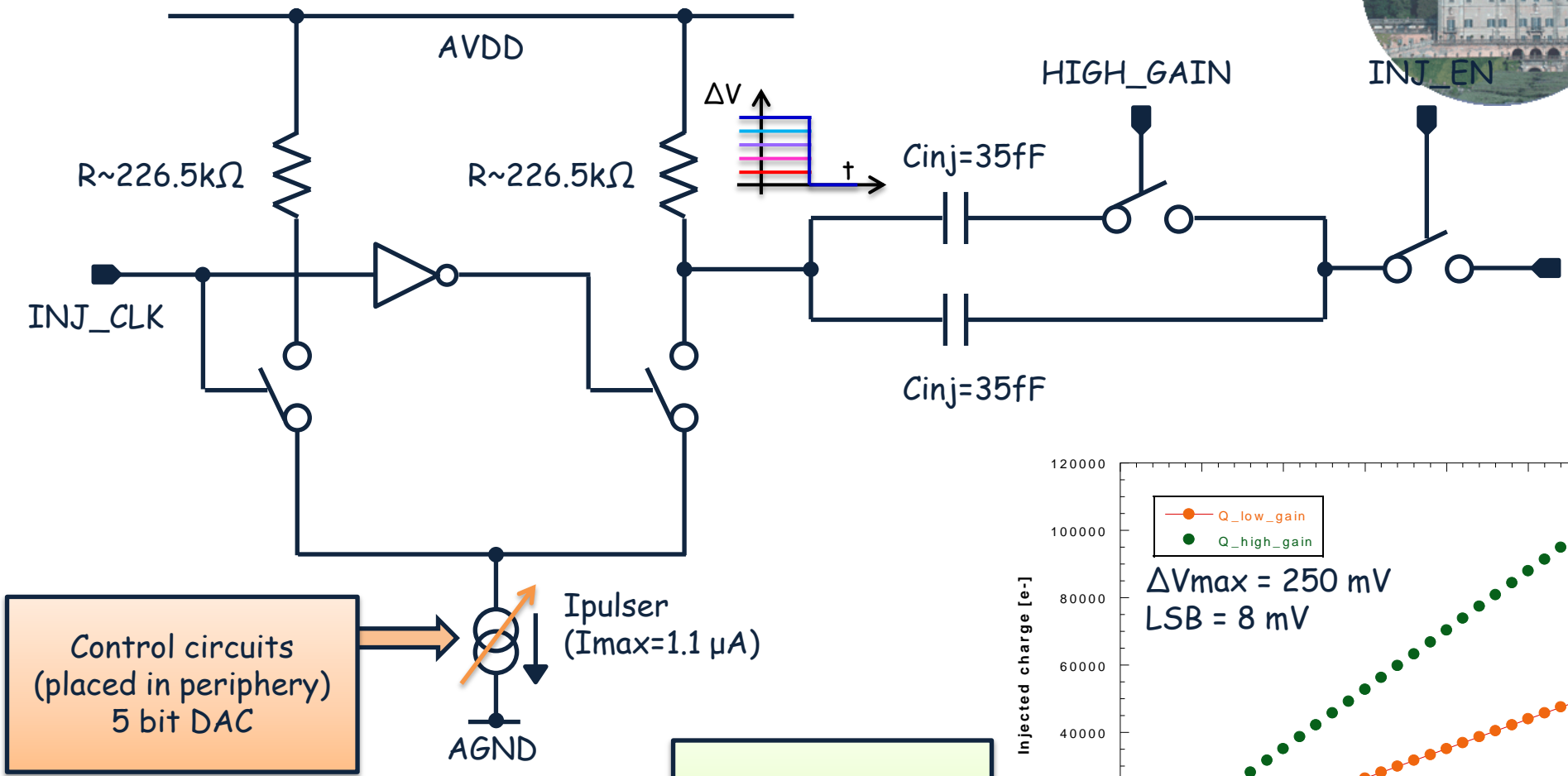
Threshold Correction Scheme



- B0 ÷ B3 bits set by means of a shift register
- Threshold dispersion before/after correction: 560 e⁻/65e⁻

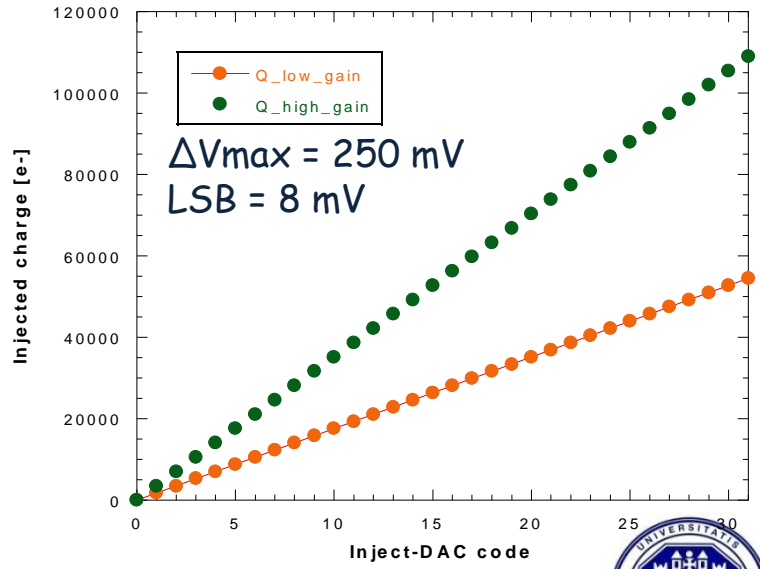


Charge Injection Circuit (In the Pixel Cell)



Control circuits
(placed in periphery)
5 bit DAC

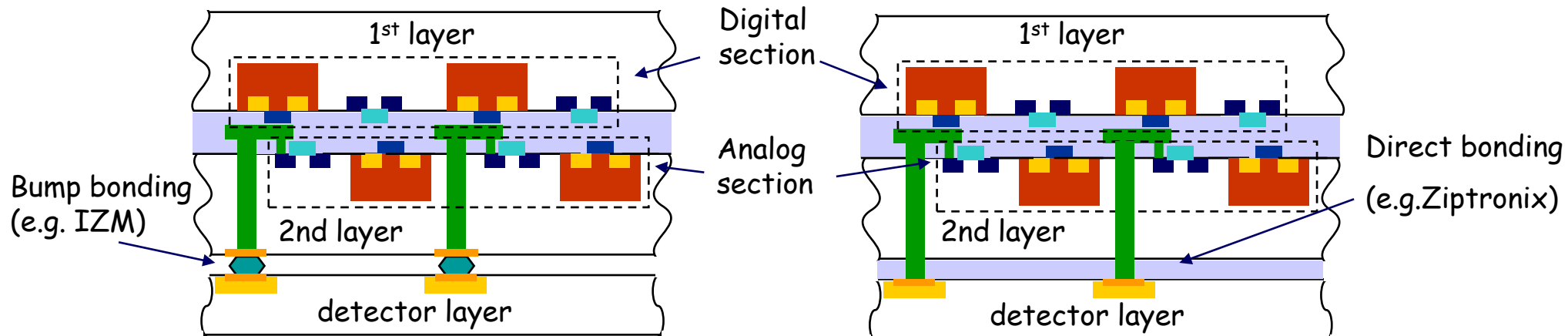
From MC simulations:
|DNL|_{max} = 0.12 LSB
|INL|_{max} = 0.35 LSB



3D Hybrid Pixels



- Development of a 3D front-end chip to be vertically integrated with fully depleted detectors through some more (bump bonding) or less (direct bonding) standard technique



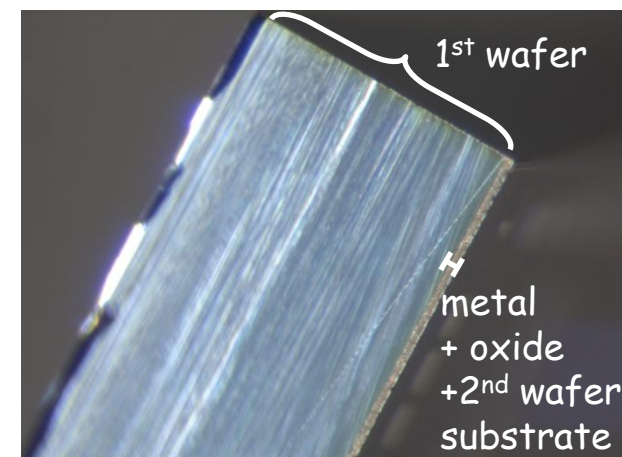
- Larger signal available from the detector ($\geq 4000 e^-$ for 200 μm thickness)
- More advantageous trade-off between S/N and dissipated power



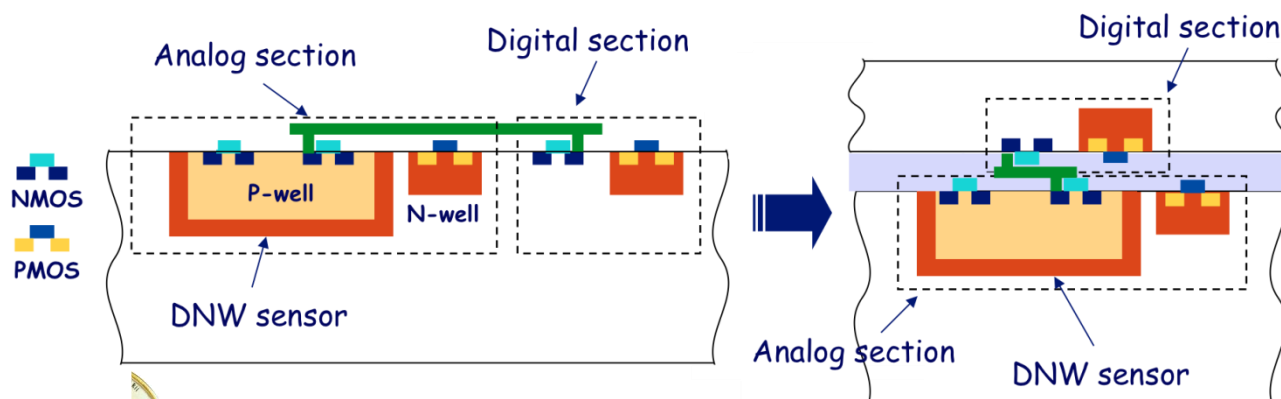
From 2D to 3D DNW MAPS



Photograph of a 3D vertically integrated chip



- Cell functionalities are split onto two different CMOS layers
→ higher functional density at the pixel level
- Sensor and analog front-end can be integrated in a different layer from the digital blocks
→ less digital to analog interference
- PMOS competitive n-wells can be placed on a separate layer from the sensor
→ improved collection efficiency



- The 2nd wafer thickness is about 12 μm
- More room for both analog and digital power and signal routing

